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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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of | 8 Sheet

	Complete If Known	
Application Number	09/970,453	
Filing Date	October 2, 2001	
First Named Inventor	Eyal, Shulamit	
Art Unit	1641	
Examiner Name	Cook, Lisa V.	
Attorney Docket Number	20174C-002410US	

 	-		U.S. PATENT DO	CUMENTS+	
Examiner initials*	Cite No.	Document Number Number Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Unes, Where Relevant Passages or Relevant Figures Appear
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For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 18 if possible.

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TRADESABeditute for torm 1449APTO Complete If Known 09/970,453 **Application Number** INFORMATION DISCLOSURE October 2, 2001 Filing Date Eyal, Shulamit STATEMENT BY APPLICANT First Named Inventor 1641 Art Unit Cook, Lisa V. (use as many sheets as necessary) Examiner Name 20174C-002410US **Attorney Docket Number** Sheet

			U.S. PATENT DO	CUMENTS+	
		Document Number		N of Outsides or	Pages, Columns, Lines, Where
Examiner Initials*	Cite No.	Number Kind Code ² (# known)	Publication Date MM-DD-YYYY	Name of Patenties or Applicant of Cited Document	Relevant Passages or Relevant Figures Appear
WCI	A42	US-6,123,769	09-26-2000	Sanjoh	
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LYC.	A48	US-6,409,832 B1	06-25-2002	Weigl et al.	

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Seedon	Cite	Foreign Patent Document				Name of Patentee or	Pages, Columns, Lines, Where Relevant	
Examiner initials*	No. 1 Country Code 3 Number 4 Rind Code (# known) MM-DD-YYYY	Publication Date MM-DD-YYYY	Applicant of Cited Document	Passages or Relevant Figures Appear	70			
LYC	B1	EPO	EP 0 592 094	A2	04-13-1994			
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	B11	PCT	WO 99/17093	A1	04-08-1999			
HC	B12	PCT	WO 00/60345	A1	10-12-2000			

Examiner Signature	Ofisa. LC	eck	Date Considered	1/11/05

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 3 of 8

Complete if Known					
Application Number	09/970,453				
Filing Date	October 2, 2001				
First Named Inventor	Eyal, Shulamit				
Art Unit	1641				
Examiner Name	Cook, Lisa V.				
Attorney Docket Number	20174C-002410US				

		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials *	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Т2
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PASSIBLE for form 1449B/PTO Complete if Known 09/970,453 Application Number INFORMATION DISCLOSURE October 2, 2001 Filing Date STATEMENT BY APPLICANT Eyal, Shulamit First Named Inventor 1641 Art Unit Cook, Lisa V. (use as many sheets as necessary) Examiner Name 20174C-002410US Attorney Docket Number of | 8 Sheet

		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials *	Cite No.1	include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
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Examiner Signature	Aisa. V	Cook	Date Considered	1/11/05

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INFORMATION DISCLOSURE

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Complete if Known				
Application Number	09/970,453			
Filing Date	October 2, 2001			
First Named Inventor	Eyal, Shulamit			
Art Unit	1641			
Examiner Name	Cook, Lisa V.			
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Examiner Signature	Olisa. X	Cock	Date Considered	1/11/05

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Art Unit	1641			
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LYCY	C37	PETHIG & MARKX "Applications of dielectrophoresis in biotechnology," Tibtech, 15:426-432 (1997).	
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Examiner Signature	Riss. K	look	Date Considered	1/11/05

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Examiner Signature	Risa. Klook	Date Considered	1/11/05

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LVC	C62	Zengerle et al., "Performance Simulation of Microminiaturized Membrane Pumps," from 7th International Conference on Solid-State Sensors and Actuators held 6/7-10/93 in Yokohama Japan, pages 106-109			

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